IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Takashi OZAKI, et al.

Serial Number: Not Yet Assigned

(§371 of International Application PCT/JP2003/008097)

Filed: December 23, 2004

For: SUBSTRATE TREATING APPARATUS AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

December 23, 2004

Sir:

In compliance with 37 CFR 1.56, Applicants call to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449 and cited in the enclosed international search report. Reference AA is cited in the International Search Report.

In the event there are any fees due in connection with the filing of this paper, please charge Deposit Account No. <u>01-2340</u>.

Respectfully submitted,

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PATENT TRADEMARK OFFICE

Enclosures: PTO-1449; International Search Report

INFORMATION DISCLOSURE STATEMENT PTO-1449 Atty. Docket No. 040509

Serial No. New Application

Applicant(s): Takashi OZAKI, et al.

Filing Date: December 23, 2004

Group Art Unit: Not Yet Assigned

U.S. PATENT DOCUMENTS

Examiner Initial		Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
	AA	6,099,302	Jh. Hong, et al.	08/08/00			
	AB						
	AC						
	AD				20		

FOREIGN PATENT DOCUMENTS

	Document No.	Date	Country	Translation (Yes or No)
AE	7-109574	04/25/95	Japan	Cited in the International Search Report
 AF	2000-106349	04/11/00	Japan	Cited in the International Search Report
 AG	2000-182979	06/30/00	Japan	Cited in the International Search Report
 AH	2000-91406	03/31/00	Japan	Cited in the International Search Report
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